



WORLD TRADE ORGANIZATION
ORGANISATION MONDIALE DU COMMERCE
ORGANIZACIÓN MUNDIAL DEL COMERCIO

Reference: WLI/100

8 February 2002

**MARRAKESH AGREEMENT ESTABLISHING
THE WORLD TRADE ORGANIZATION
DONE AT MARRAKESH ON 15 APRIL 1994**

GENERAL AGREEMENT ON TARIFFS AND TRADE 1994

**CERTIFICATION OF MODIFICATIONS AND RECTIFICATIONS TO
SCHEDULE CXXXIX – REPUBLIC OF BULGARIA**

TRANSMISSION OF CERTIFIED TRUE COPY

I have the honour to furnish herewith a certified true copy of the Certification of Modifications and Rectifications to Schedule CXXXIX – Republic of Bulgaria, effective **28 January 2002**.

Mike Moore
Director-General

02-0651

WT/Let/414

**SCHEDULES OF TARIFF CONCESSIONS TO THE
GENERAL AGREEMENT ON TARIFFS AND TRADE 1994**

CERTIFICATION OF MODIFICATIONS AND RECTIFICATIONS

SCHEDULE CXXXIX – REPUBLIC OF BULGARIA

WHEREAS the CONTRACTING PARTIES to the General Agreement on Tariffs and Trade 1947 adopted, on 26 March 1980, a Decision on Procedures for Modification and Rectification of Schedules of Tariff Concessions (BISD 27S/25);

WHEREAS in accordance with the provisions of the above-mentioned Decision, a draft containing modifications and rectifications to Schedule CXXXIX – Republic of Bulgaria was communicated to all Members of the World Trade Organization in document G/MA/TAR/RS/76 on 2 March 2001;

IT IS HEREBY CERTIFIED that the modifications and rectifications to Schedule CXXXIX – Republic of Bulgaria are established in conformity with the above-mentioned Decision.

Upon receipt by the Director-General of the notification by the Government of the Republic of Bulgaria that the internal procedures in the Republic of Bulgaria have been completed, the annexed modifications and rectifications are effective as of **28 January 2002**.

This Certification is deposited with the Director-General of the World Trade Organization, who shall promptly furnish a certified true copy to each Member of the World Trade Organization. It shall be registered in accordance with the provisions of Article 102 of the Charter of the United Nations.

DONE at Geneva this eighth day of February, two thousand and two.

Mike Moore

Certified copy:

Director-General

SCHEDULE CXXXIX - THE REPUBLIC OF BULGARIA

This Schedule is authentic only in the English language

HS/BCT2000	Description	Base rate	Bound rate	Implementation	ODCs
381800	Chemical elements doped for use in electronics, in the form of discs, wafers or similar forms; chemical compounds doped for use in electronics				
381800100	- Doped silicon	10	0	2001	0
381800900	- Other	10	0	2001	0
702000	Other articles of glass				
702000050	- Quartz reactor tubes and holders designed for insertion into diffusion and oxidation furnaces for production of semiconductor wafers	35	0	2001	0
702000100	- Of fused quartz or other fused silica				
702000300	- Of glass having a linear coefficient of expansion not exceeding 5 x 10 ⁻⁶ per Kelvin within a temperature range of 0 °C to 300 °C				
702000800	- Other				
8419	Machinery, plant or laboratory equipment, whether or not electrically heated, for the treatment of materials by a process involving a change of temperature such as heating, cooking, roasting, distilling, rectifying, sterilizing, pasteurizing, steaming, drying, evaporating, vapourising, condensing or cooling, other than machinery or plant of a kind used for domestic purposes; instantaneous or storage water heaters, non-electric:				
841989	-- Other				
841989100	--- Cooling towers and similar plant for direct cooling (without a separating wall) by means of recirculated water				
841989150	--- Apparatus for rapid heating of semiconductor wafers	35	0	2001	0
841989200	--- Apparatus for chemical vapour deposition on semiconductor wafers	35	0	2001	0
841989250	--- Apparatus for physical vapour deposition by electronic beam or evaporation on semiconductor wafers	35	0	2001	0
841989270	--- Apparatus for chemical vapour deposition on LCD substrates				
841989300	--- Vacuum-vapour plant for the deposition of metal				
841989980	--- Other				
841990	- Parts				
841990100	-- Of heat exchange units, for use in civil aircraft				
841990250	-- Of sterilizers of subheading 8419 20 00 0 and of apparatus of subheading 8419 89 15 0, 8419 89 20 0 or 8419 89 25 0				
841990250	-- For apparatus of subheading 8419 89 15 0 to 841989 25 0	7	0	2001	0
841990500	-- For apparatus of subheading 8419 89 27 0				
841990800	-- Other				
8421	Centrifuges, including centrifugal dryers; filtering or purifying machinery and apparatus, for liquids or gases:				
842119	-- Other				
842119100	--- For use in civil aircraft				
842119910	--- Other				
842119910	----- Centrifuges of a kind used in laboratories				
842119940	----- Centrifuges of a kind used in the manufacturing of semiconductor wafers	35	0	2001	0

HS/BCT2000	Description	Base rate	Bound rate	Implementation	ODCs
842119990	---- Other				
	- Parts				
842191	-- Of centrifuges, including centrifugal dryers				
842191100	---- For apparatus of subheading 8421 19 94 0	35	0	2001	0
842191300	---- For apparatus of subheading 8421 19 99 0				
842191900	---- Other				
842199000	-- Other				
8424	Mechanical appliances (whether or not hand-operated) for projecting, dispersing or spraying liquids or powders; fire extinguishers, whether or not charged; spray guns and similar appliances; steam or sand blasting machines and similar jet projecting machines:				
842489	-- Other				
842489200	---- Spraying appliances for etching, stripping or cleaning semiconductor wafers	35	0	2001	0
842489300	---- Deflash machines for cleaning and removing contaminants from the metal leads of semiconductor packages prior to the electroplating process	35	0	2001	0
842489950	---- Other				
842490	- Parts				
842490100	-- Of apparatus of subheading 8424 89 20 0	35	0	2001	0
842490300	-- Of apparatus of subheading 8424 89 30 0				
842490900	-- Other				
8428	Other lifting, handling, loading or unloading machinery (for example, lifts, escalators, conveyors, teleferics) :				
842839	-- Other				
842839100	---- For use in civil aircraft				
	---- Other				
842839910	----- Roller conveyors				
842839930	----- Automated material handling machines for transport, handling and storage of semiconductor wafers, wafer cassettes, wafer boxes and other material for semiconductor devices	20.5	0	2001	0
842839980	----- Other				
8431	Parts suitable for use solely or principally with the machinery of heading Nos 8425 to 8430 :				
843139	-- Other				
843139100	---- Of rolling-mill machinery of subheading 8428 90 30 0				
843139900	---- Other				
843139900	---- Of machinery of subheading 8428 39 93 0	9	0	2001	0
8456	Machine-tools for working any material by removal of material, by laser or other light or photon beam, ultrasonic, electro-discharge, electro-chemical, electron beam, ionic-beam or plasma arc processes :				
845610	- Operated by laser or other light or photon beam processes				
845610100	--- Of a kind used in the manufacturing of semiconductor wafers or devices	35	0	2001	0